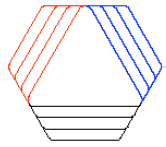


TriFact
Solutions, Inc.

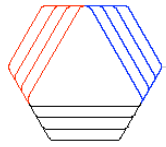
**Third Party Resist Supplier Evaluation of
TriFact Solutions, Inc.
DI Water Heater Model TFS 4000-TP
Unexposed Resist Defects**



TriFact
Solutions, Inc.

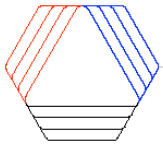
Project Objective

- **Study the effect of a heated deionized (DI) water rinse on the formation of post develop defects on unexposed resist defects.**



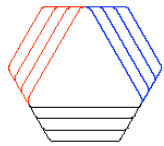
Equipment

- TEL Mark 8 coat/develop tool
- TriFact Solutions DI water Heater Model TFS 2000-TP
- Tridak Low Volume Dispense Assembly
- ASML PAS5500/850 stepper
- K-T8100 Top Down CD SEM
- K-T2135 Defect Inspection tool
 - Narrowband illumination with a Hg-Xenon light source and filtered wavelength.
 - Inspection wavelength around 580nm.



KLA-Tencor2135 Defect Inspection Parameters

- KLA2135 Defect Inspection tool
 - Pixel setting: **0.25** μm
 - Inspection Mode: Array
 - Threshold: 20
 - Filter set: f2
 - Inspected area: **69.07** sq./cm. Patterned Resist
 - Area **35.85** sq./cm. Unexposed Resist
 - Area **35.06** sq./cm. Bulk Exposed
 - Resist Area

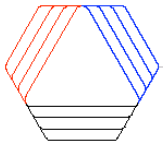


Results Summary Table

Unexposed Resist Area Defects

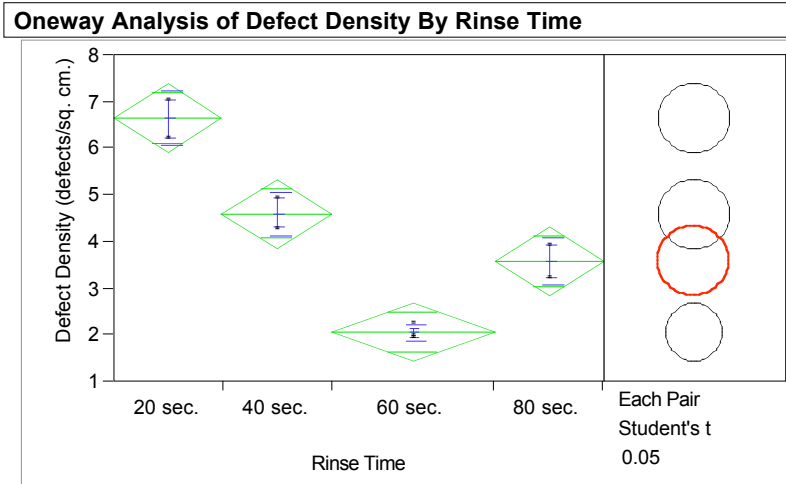
| DI Water Rinse Time | Standard Rinse Temperature | | Heated Rinse Temperature | |
|---------------------|----------------------------|----------------------------------|--------------------------|----------------------------------|
| | Defect Count | Defect Density (defects/sq. cm.) | Defect Count | Defect Density (defects/sq. cm.) |
| 20 sec. | 224 | 6.25 | 110 | 3.07 |
| 20 sec. | 253 | 7.06 | 90 | 2.51 |
| 20 sec. | | | | |
| 40 sec. | 177 | 4.94 | 134 | 3.74 |
| 40 sec. | 153 | 4.27 | 91 | 2.54 |
| 40 sec. | | | 98 | 2.73 |
| 60 sec. | 71 | 1.98 | 77 | 2.15 |
| 60 sec. | 70 | 1.95 | 77 | 2.15 |
| 60 sec. | 81 | 2.26 | 75 | 2.09 |
| 80 sec. | 116 | 3.24 | 63 | 1.76 |
| 80 sec. | 141 | 3.93 | 67 | 1.87 |
| 80 sec. | | | 88 | 2.45 |

The heater setting is at 40°C but the actual temperature at the DI water rinse nozzle is 36°C. This is due to the length of exposed tubing between the heater assembly and the dispense tip. For this evaluation, the heater was not able to be configured closer to the DI water dispense nozzle.



JMP Analysis Results of Defect Density's Unexposed Resist Area Defects

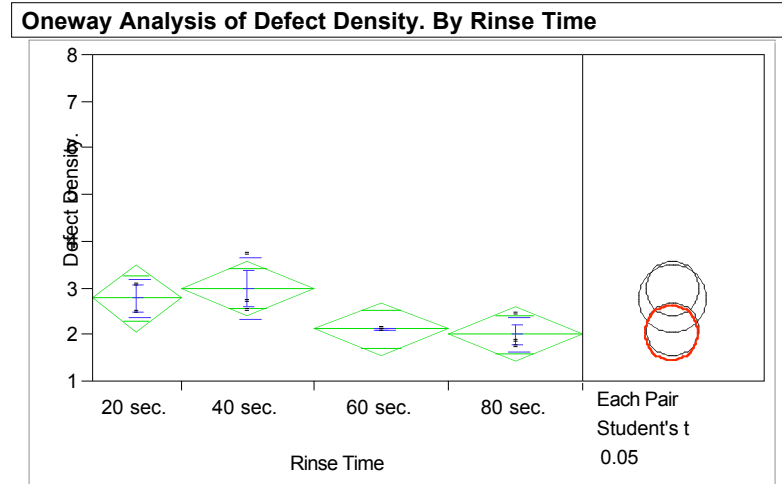
Standard DI Water Rinse Temp. (21°C)



Means and Std Deviations

| Level | Number | Mean | Std Dev | Std Err Mean | Lower 95% | Upper 95% |
|---------|--------|---------|----------|--------------|-----------|-----------|
| 20 sec. | 2 | 6.65500 | 0.572756 | 0.40500 | 1.509 | 11.801 |
| 40 sec. | 2 | 4.60500 | 0.473762 | 0.33500 | 0.348 | 8.862 |
| 60 sec. | 3 | 2.06333 | 0.170978 | 0.09871 | 1.639 | 2.488 |
| 80 sec. | 2 | 3.58500 | 0.487904 | 0.34500 | -0.799 | 7.969 |

Heated DI Water Rinse Temp. (40°C)



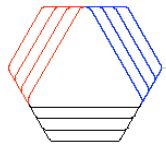
Means and Std Deviations

| Level | Number | Mean | Std Dev | Std Err Mean | Lower 95% | Upper 95% |
|---------|--------|---------|----------|--------------|-----------|-----------|
| 20 sec. | 2 | 2.79000 | 0.395980 | 0.28000 | -0.768 | 6.3477 |
| 40 sec. | 3 | 3.00333 | 0.645006 | 0.37239 | 1.401 | 4.6056 |
| 60 sec. | 3 | 2.13000 | 0.034641 | 0.02000 | 2.044 | 2.2161 |
| 80 sec. | 3 | 2.02667 | 0.370720 | 0.21404 | 1.106 | 2.9476 |

With A standard rinse temperature, increasing the rinse time reduces post develop defects.

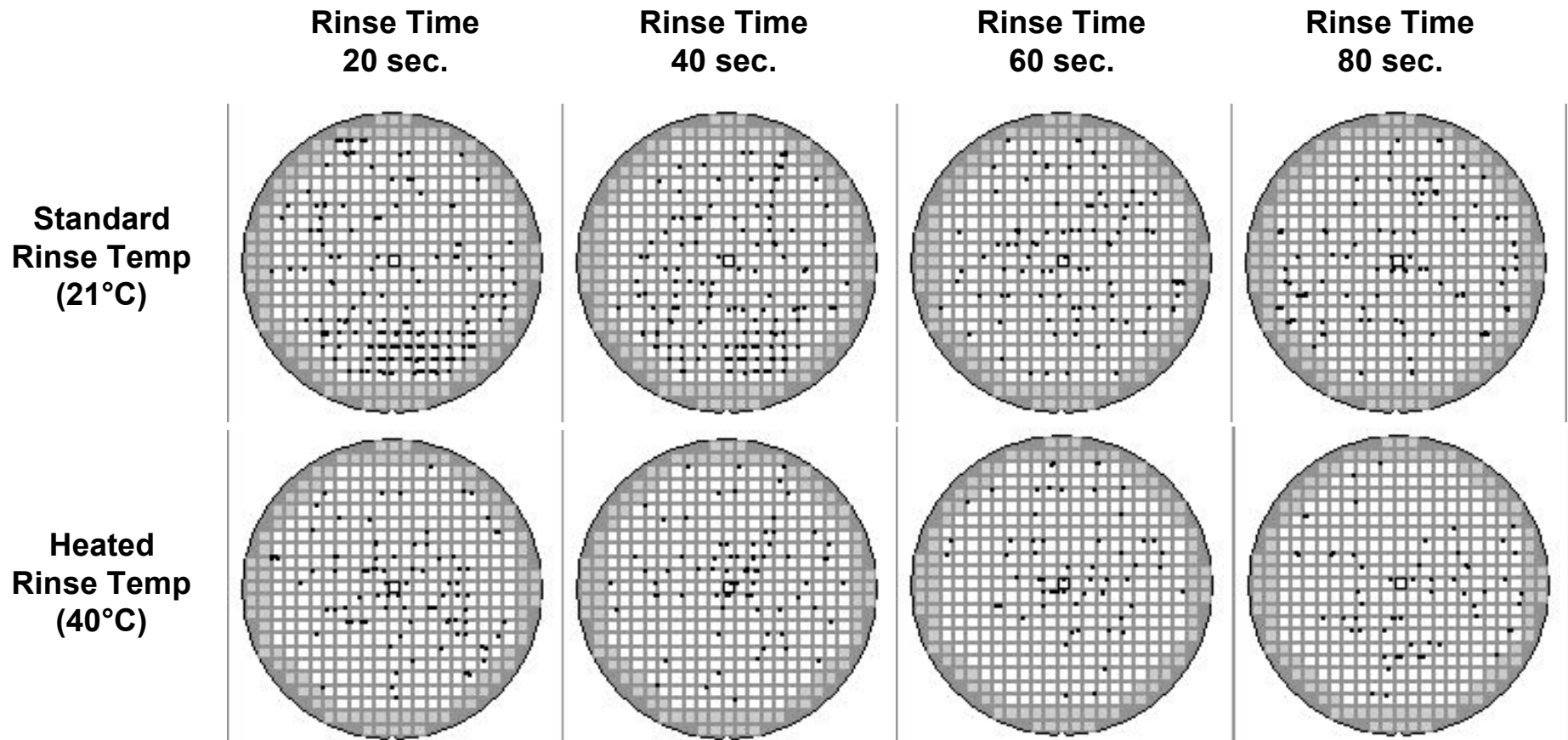
A heated DI water rinse produced lower counts at a shorter rinse and continues to maintain or reduce that count with extended rinse time. A heated DI water rinse at 20 sec was equivalent to a standard rinse at 60 second.

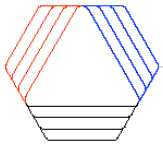
Note: 40°C is the set point temperatures on the heating assembly. Actual temperature at the Nozzle is 36°C.



Wafer Maps

Unexposed Resist Area Defects

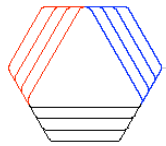




Classification Codes

Unexposed Resist Area Defects

- **Sm Dark – Small dark point defects (<math><0.25\mu\text{m}</math> in size).**
- **Sm Bright – Small light point> defects (<math><0.25\mu\text{m}</math> in size).**
- **Rnd/Med Dark – Round and darker than the background.**
- **Rnd/Med Bright – Round and lighter than the background.**
- **Type 44 – Round bright center with large, darker halo.**

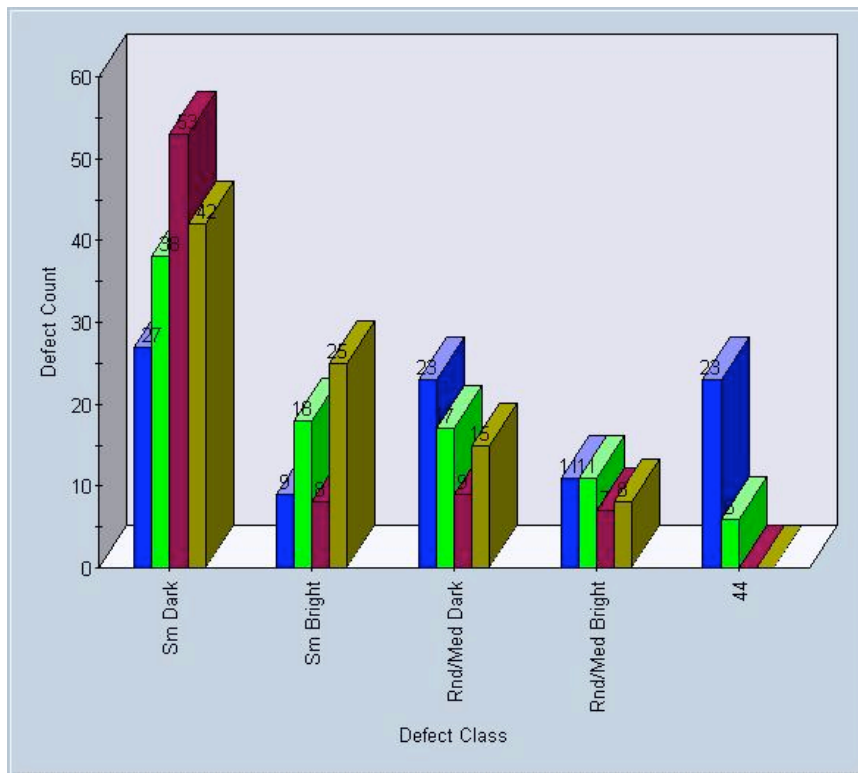


Pareto Charts

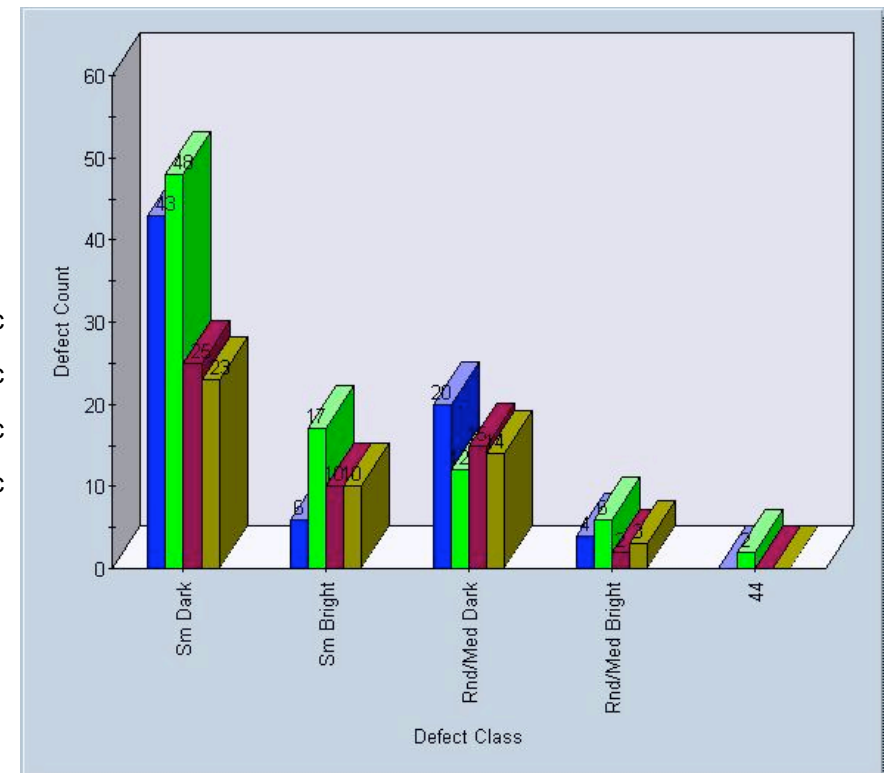
Unexposed Resist Area Defects

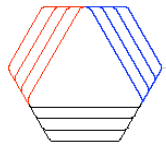
One wafer classified per process condition. Up to 100 defects classified per wafer.

Standard Rinse Temperature (21°C)



Heated Rinse Temperature (40°C)

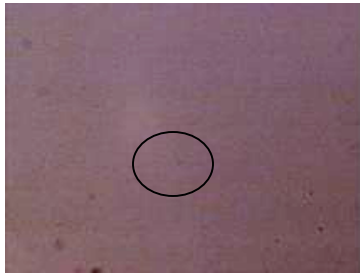




TriFact
Solutions, Inc.

Optical Images of Defect Types Unexposed Resist Area Defects

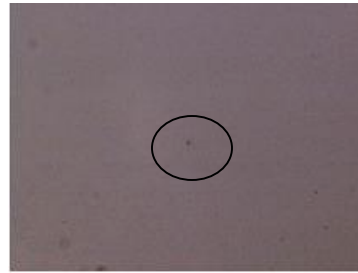
Sm dark



Sm bright



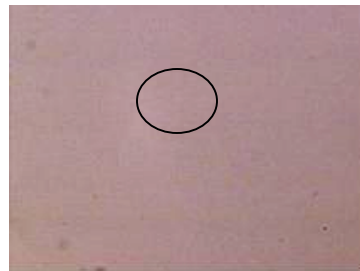
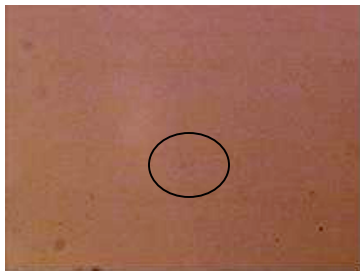
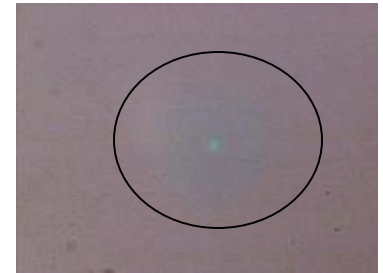
Rnd/Med Dark

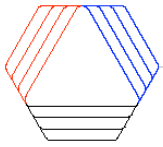


Rnd/Med bright



Type 44





Results Summary

Unexposed Resist Area Defects

- **Analysis of the defect density's show:**
 - Using a standard rinse temperature, increasing the rinse time reduces post develop defects.
 - A heated DI water rinse produced lower counts at a shorter rinse and continues to maintain or reduce that count with extended rinse time.
 - A heated DI water rinse at 20 sec was equivalent to a standard rinse at 60 second.
- **Review of defects show:**
 - Using a standard rinse temperature, increasing the rinse time saw in increase in Sm Dark and Sm Bright defects and a reduction in Rnd/Med darks and Type 44 defects.
 - A heated DI water rinse reduced Sm Dark and Rnd/Med Dark defects.